

Appl. No. 09/923,720

Amdt. Dated January 13, 2004

Reply to Office Action of October 14, 2003

SPECIFICATION AMENDMENTS

Please replace the last two paragraphs on page 22 with the following three amended paragraphs:

Fig. 8 shows a probe card in which each contact is driven individually by an actuator; ~~and~~

Fig. 9 shows a further embodiment of a test apparatus, in which the probe card is planarized or moved by external actuators[[.]]; and

Fig. 10 shows a combination of a performance board with global actuators and a probe card with dedicated actuators.

Please add the following new paragraph before the last paragraph on page 29:

A combination of the various techniques proposed is also possible. For example in Fig. 10, relatively large global actuators 4b can compensate for global tilting of the wafer or the wafer holder, and at the same time, small dedicated actuators 4a can be provided at each contact 9, which compensate for individual height differences and which permit the contacts 9 to be pushed forward toward the wafer until the electrical connections are actually produced.